

Focusing of Intense Heavy Ion Beams with Plasma Lenses

Oliver Meusel

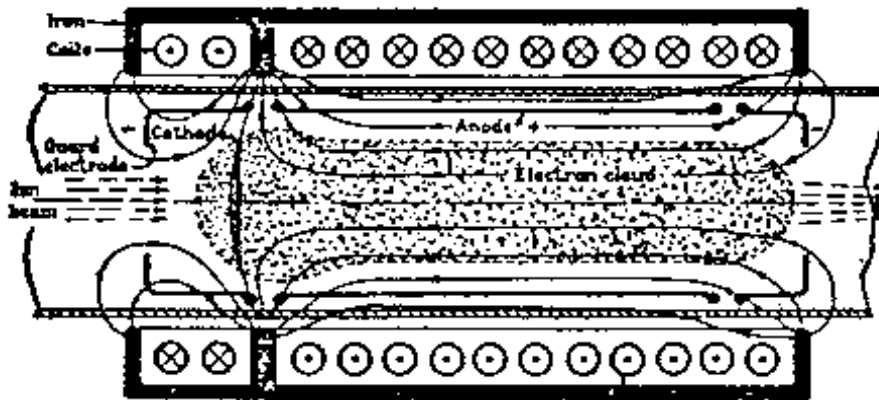
No. 405E July 19, 1947

NATURE

89

A Space-Charge Lens for the Focusing of Ion Beams

SOME time ago I proposed a magnetron of special design as a divergent lens for electron beams¹. It now appears that the same device may become useful as a very powerful concentrating lens for positive ions, particularly for ion beams of extreme energy.



MAGNETRON LENS FOR ION BEAMS



Dennis Gabor
(1900-1979)

Electrical & Electronic
Engineering Department,
Imperial College London

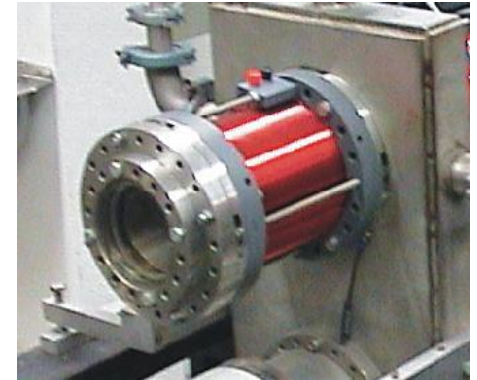
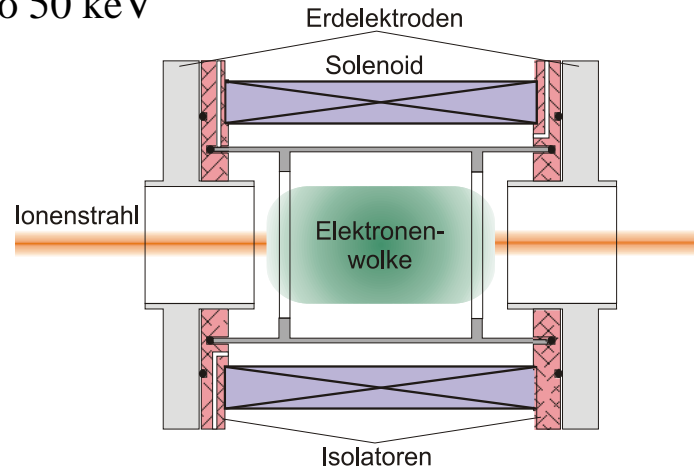
Proposal of a SCL by Gabor, July 1947

Gabor lens for beam energies up to 50 keV

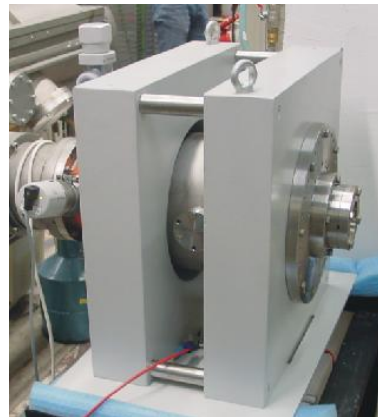
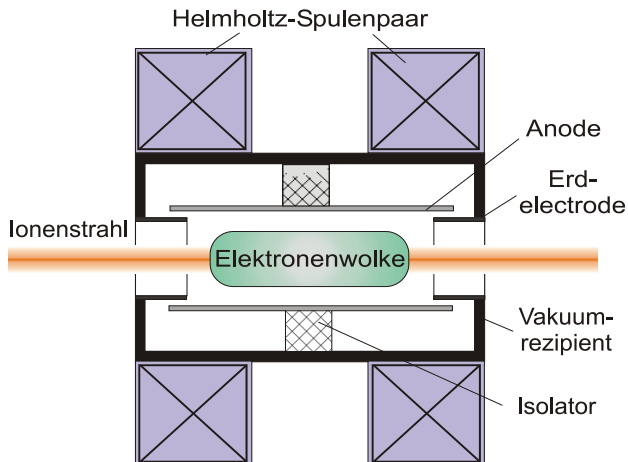
lens properties:

$$\Phi_{A,max} = 6.5kV$$

$$B_{z,max} = 48mT$$



high field Gabor lens for beam energies up to 500keV



lens properties :

$$\Phi_{A,max} = 65kV$$

$$B_{z,max} = 220mT$$

radial force balance equation

$$\frac{-m_e v_{e,\Theta}^2}{r} = -eE_r - e v_{e,\Theta} B_z$$

E_r given by Poisson equation:

$$\frac{1}{r} \frac{\partial}{\partial r} r E_r = \frac{en_e(r)}{\epsilon_0}$$

integration for $0 < r < R_p$:

$$E_r = \frac{1}{2\epsilon_0} en_e r$$

$$-\omega_e^2 = \frac{\omega_{pe}^2}{2} - \omega_e \Omega_e$$

$$\omega_e = \frac{V_{e,\Theta}}{r} \quad \text{angle velocity}$$

$$\omega_{pe}^2 = \frac{e^2 n_e}{\epsilon_0 m_e} \quad \text{plasma frequency}$$

$$\Omega_e = \frac{eB_z}{m_e} \quad \text{cyclotron frequency}$$

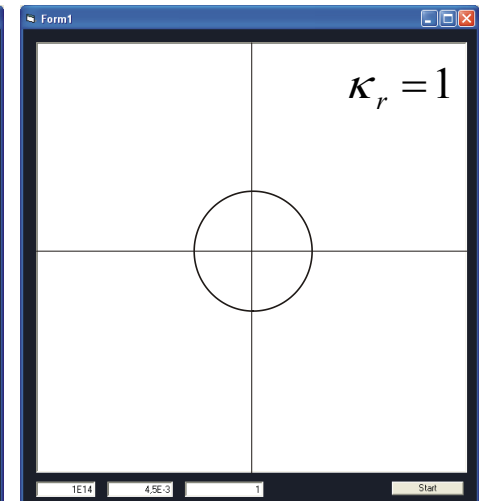
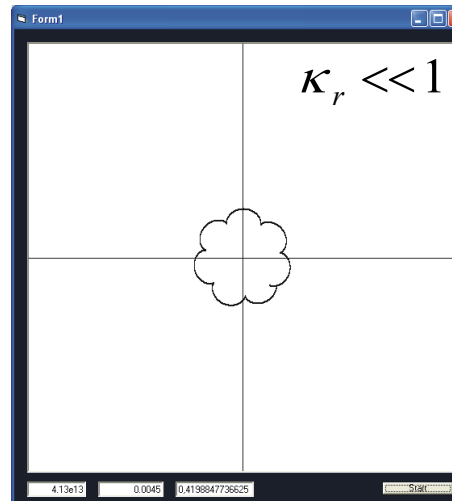
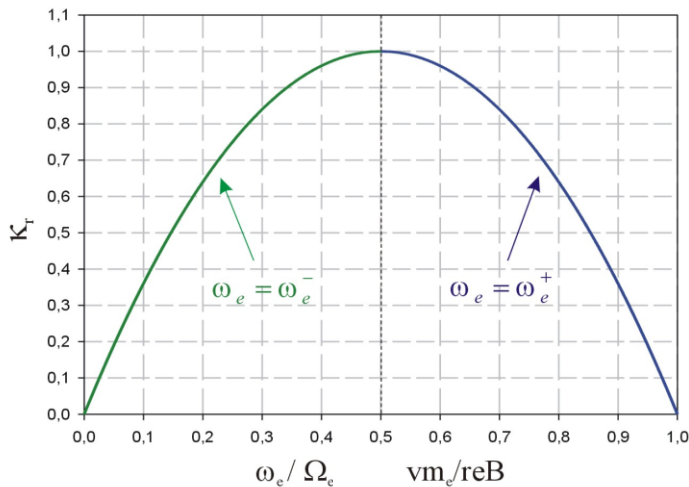
solution:
$$\omega_e = \omega^\pm = \frac{\Omega_e}{2} \left[1 \pm \left(1 - \frac{2\omega_{pe}^2}{\Omega_e^2} \right)^{\frac{1}{2}} \right]$$

maximum density by a trapping efficiency of

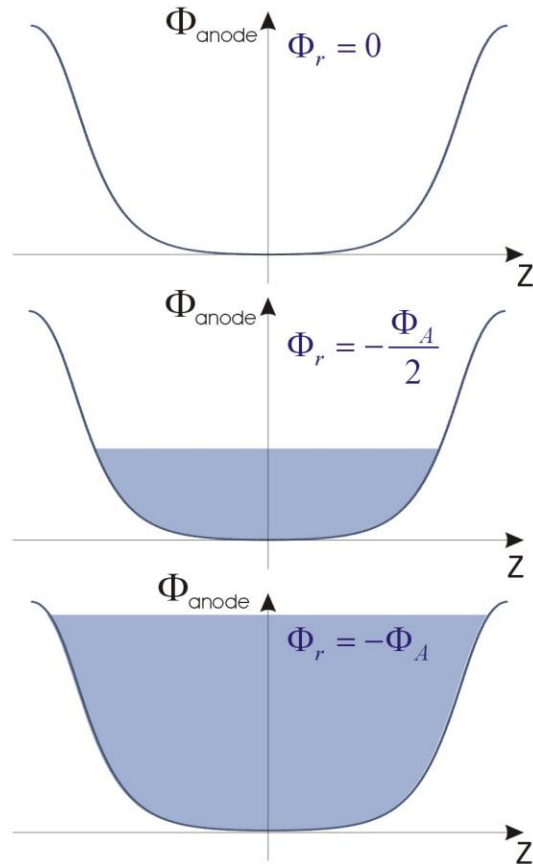
$$\kappa_r = \frac{2\omega_{pe}^2}{\Omega_e^2} = 1 \Rightarrow n_e = \frac{\epsilon_0 B_z^2}{2m_e}$$

$$\omega_e^- \cong \frac{\omega_{pe}^2}{2\Omega} = \frac{E_r}{rB_z} ; \omega_e^+ = \Omega_e$$

$$\omega_e^- = \omega_e^+ = \frac{\Omega_e}{2}$$



longitudinal potential well



Φ_r is determined from Poisson's equation:

$$-\frac{1}{r} \frac{\partial \Phi_r}{\partial r} - \frac{\partial^2 \Phi_r}{\partial r^2} = \frac{en_e(r)}{\epsilon_0}$$

integrated for $0 < r < R_p$

$$\Phi_r = -\frac{en_e r^2}{4\epsilon_0}$$

maximum density at

$$\Phi_{anode} = -\Phi_r$$

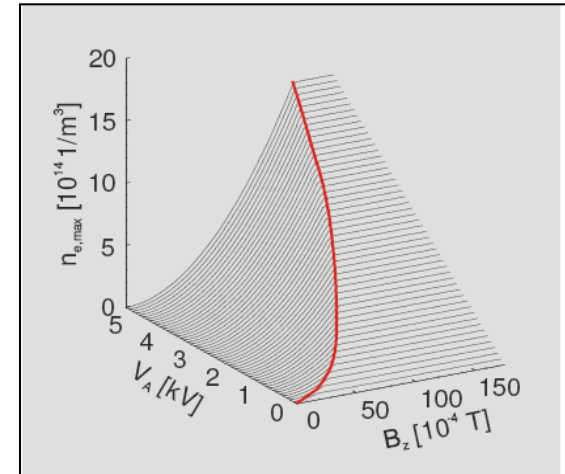
$$\Rightarrow n_e = \frac{4\epsilon_0 \Phi_A}{er^2}$$

two different simulation methods

GaborM

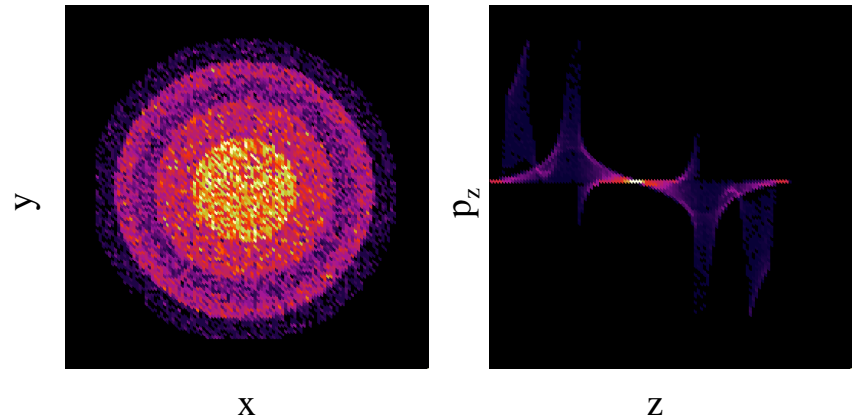
- fluid description
- steady state

$$\Phi_A = \frac{er^2 B_z^2}{8m_e}$$



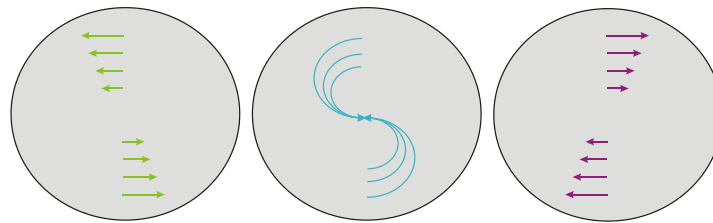
GabLensM2

- kinetic description
- dynamic processes
- 3D-Particle-In-Cell Simulation



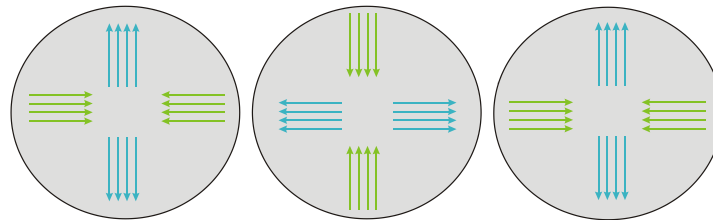
comparison of focusing strengths

Solenoid
weak focusing



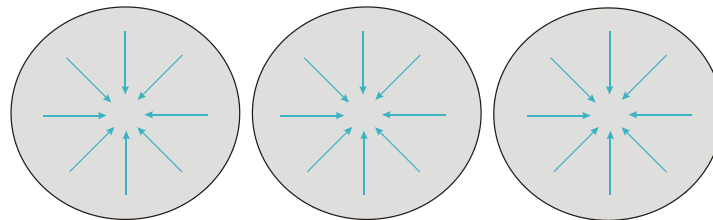
$$k = \frac{qB}{2mv}$$

MSQ / ESQ
strong
focusing/defocusing



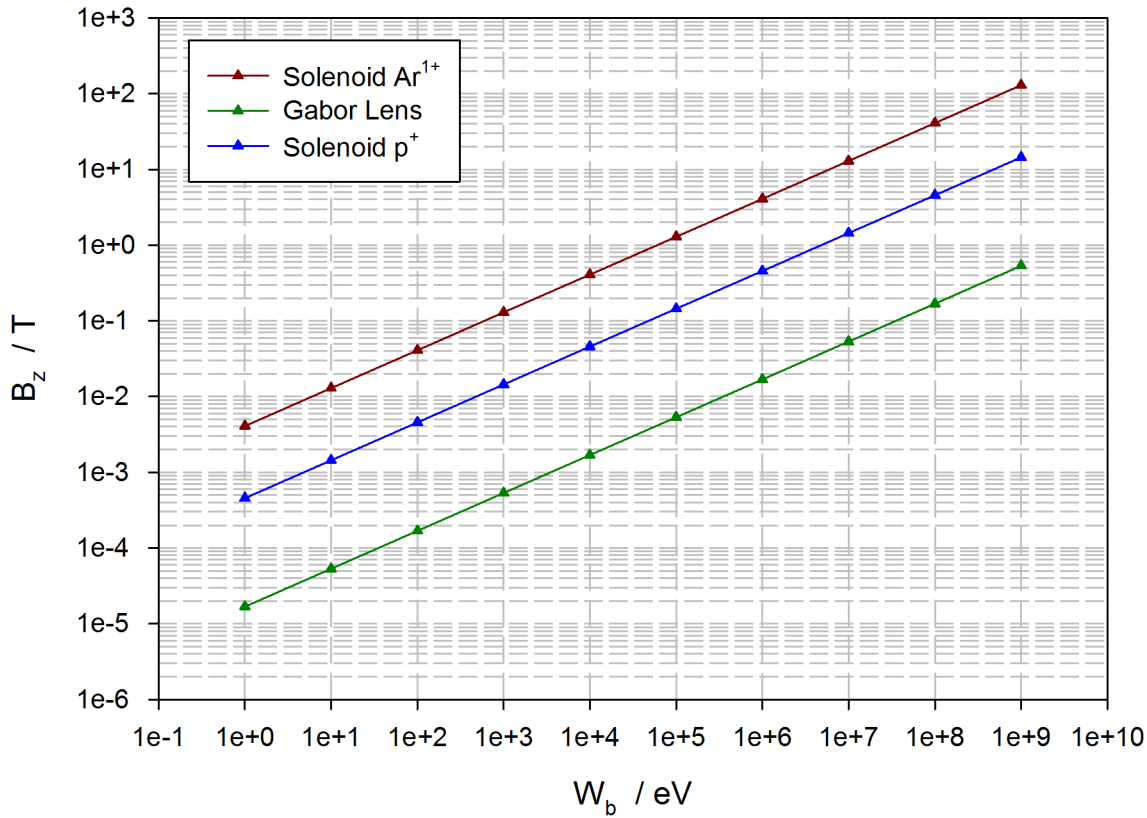
$$k = \sqrt{\frac{qg}{mv}} / k = \sqrt{\frac{qg}{mv^2}}$$

SCL
strong focusing



$$k = \sqrt{\frac{\kappa q e B_z^2}{8 m_e W_b}}$$

time →



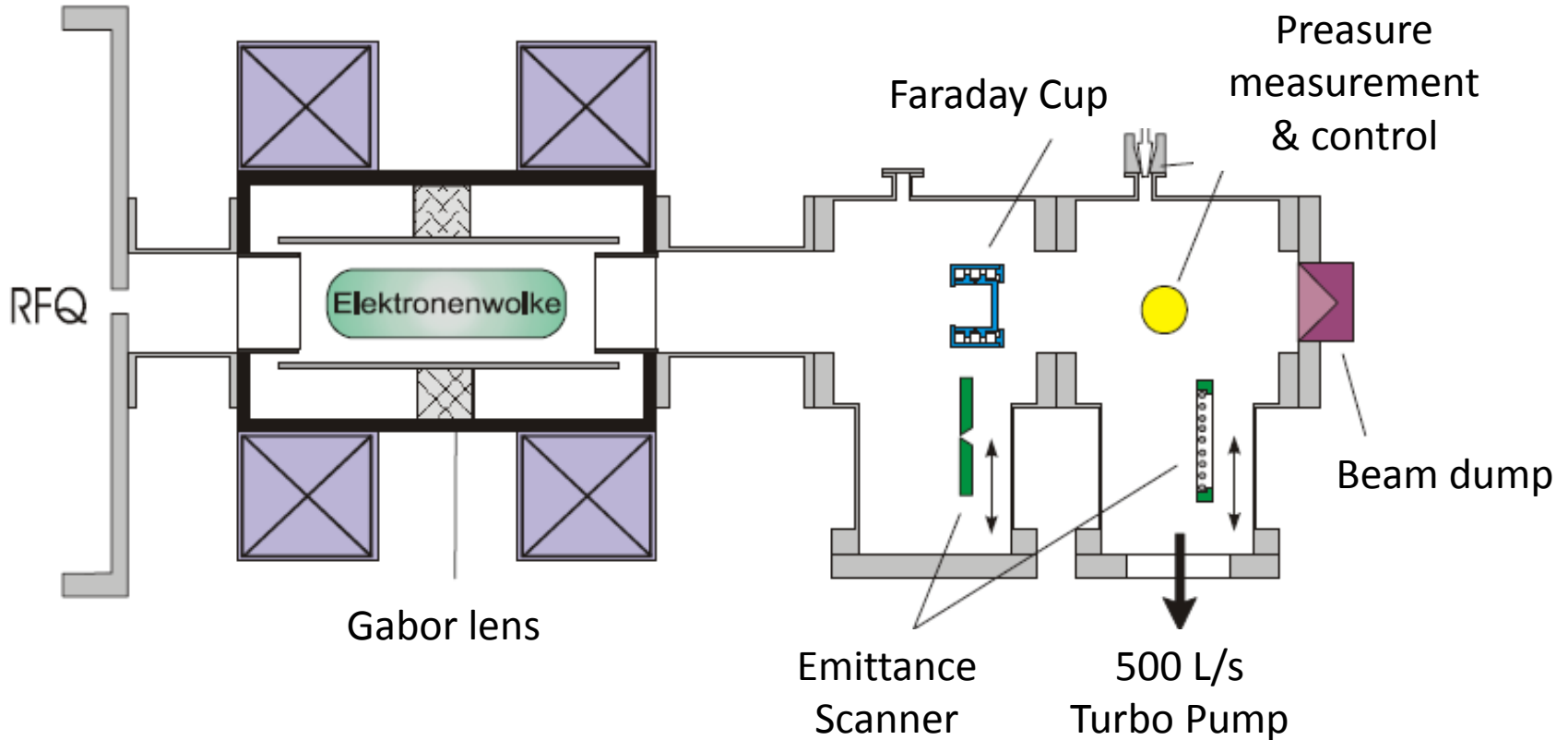
$$k = \sqrt{\frac{\kappa q^2 B_z^2}{8m_e W_b}}$$

$$k = \frac{qB}{2m_i v_i} \cdot \sqrt{\kappa \frac{m_i}{m_e}}$$

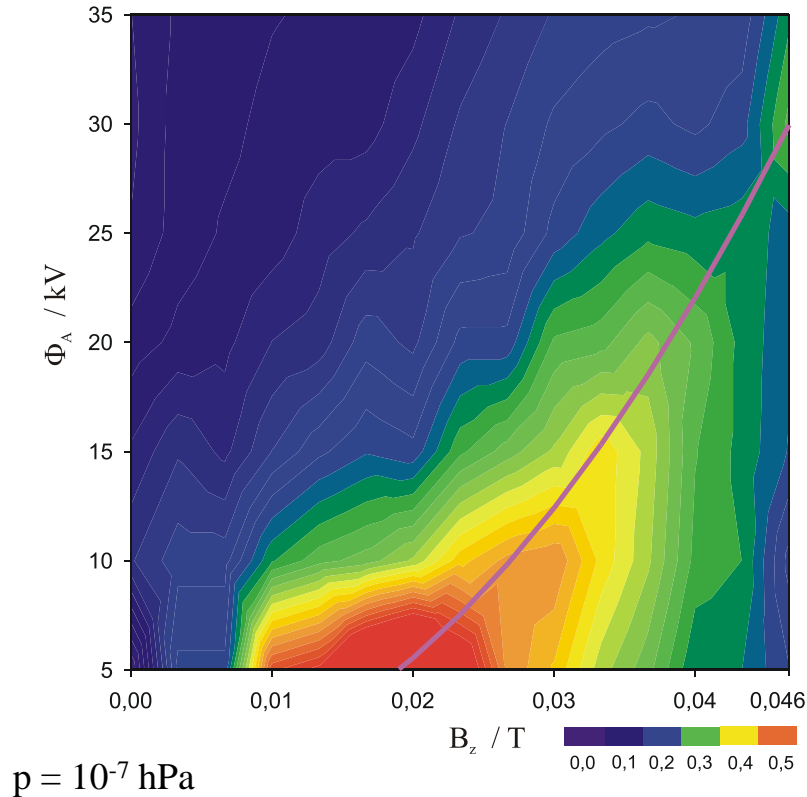
Filling degree κ depends on:

- electron temperature
- loss and production rates

focussing of micro bunches passing a Gabor lens @ 108MHz, $\Delta\phi = 60^\circ$



measurement of the electron density using an ion beam



$$\frac{1}{f} = \frac{\Delta x'}{x_0} = k^2 l = \frac{en_{e,\text{exp}}}{4\epsilon_0} \frac{l}{W_b}$$

$$\kappa_r = \frac{n_{e,\text{exp}}}{n_{e,\text{theo}}}$$

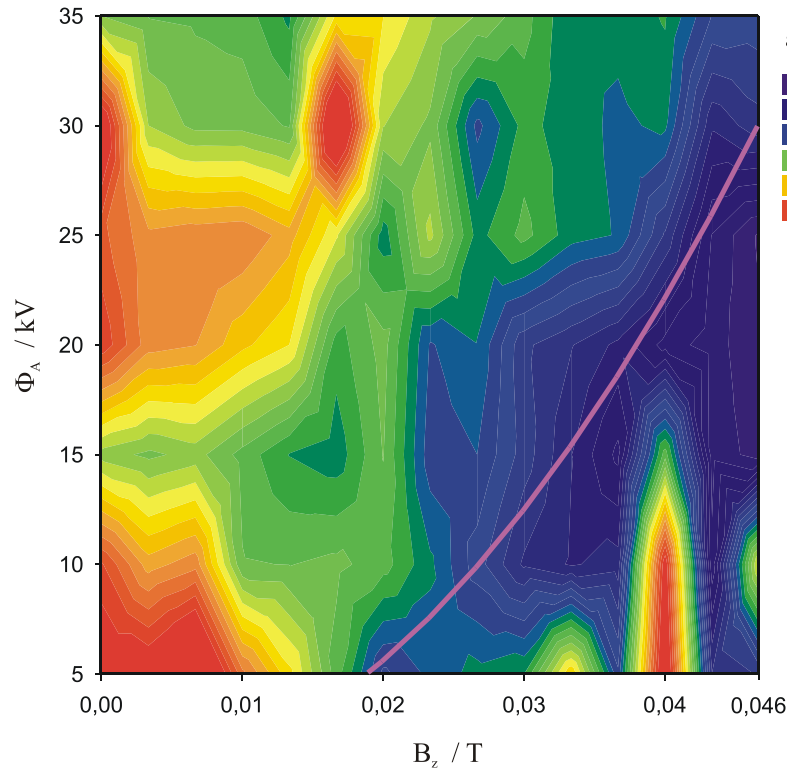
beam properties:

$$W_b = 110 \text{ keV/u}$$

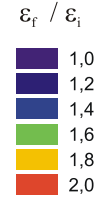
$$I = 1.2 \text{ mA}$$

He^+

characterisation of lens aberration by estimation of emittance growth



$p = 10^{-7}$ hPa



$$\epsilon_{rms} = \sqrt{\langle x^2 \rangle \langle x'^2 \rangle - \langle xx' \rangle^2}$$

$$\Delta \epsilon_{rms} = \frac{\epsilon_{rms,out}}{\epsilon_{rms,in}}$$

beam properties:

$W_b = 110$ keV/u

$I = 1.2$ mA

He^+

HSI-LEBT Upgrade

Schematic layout of the LEBT

Upgrade 0

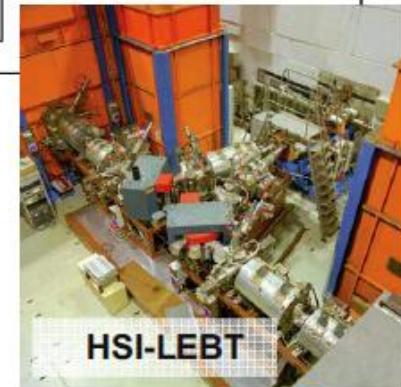
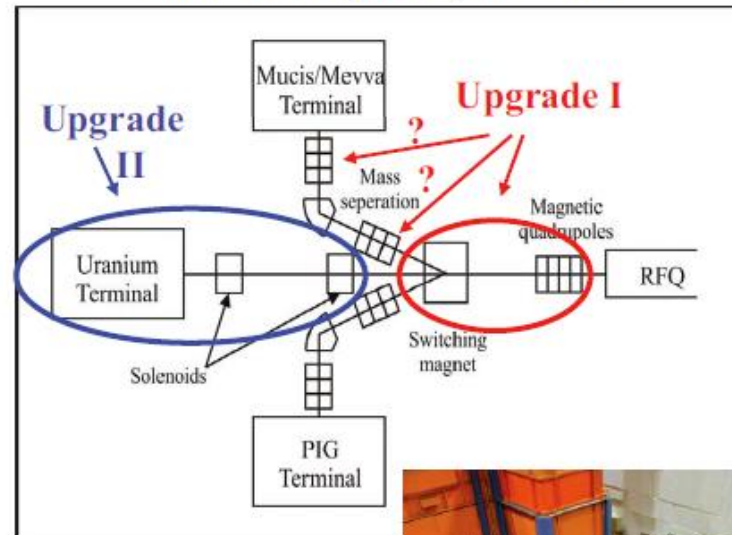
- High Current test stand measurements

Upgrade I

- Switching magnet with increased aperture
- Quadrupole quartet (matching to the RFQ) with increased apertures

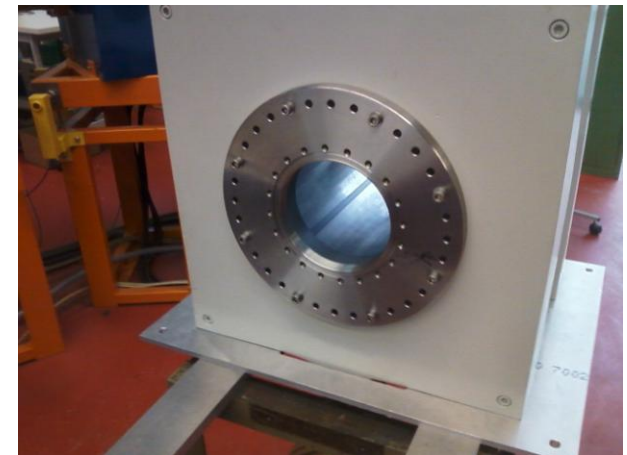
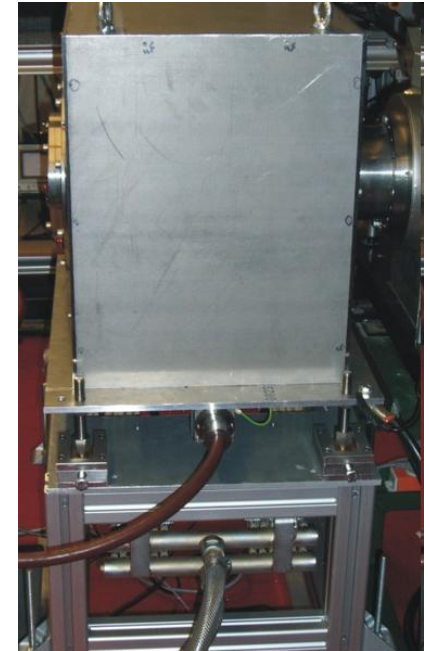
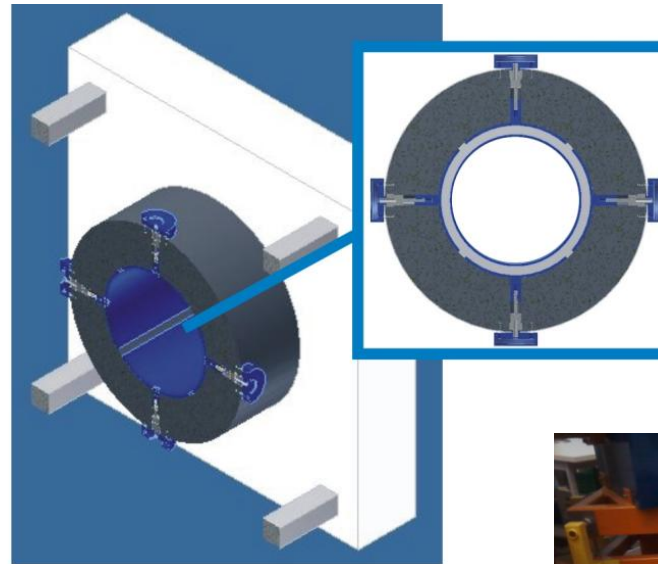
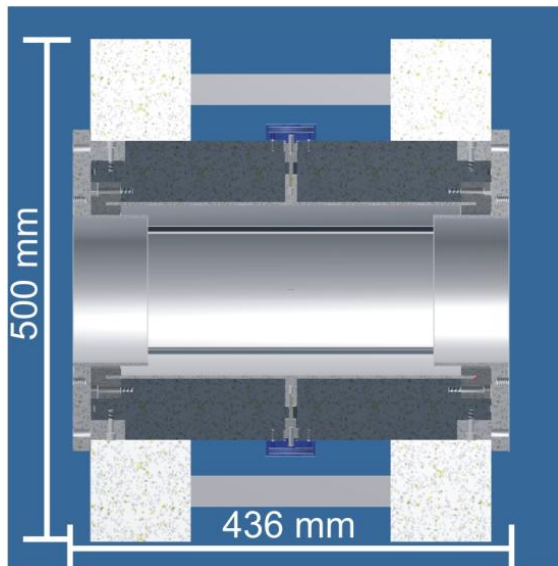
Upgrade II (**Compact LEBT**)

- Beam line with direct injection to the RFQ (integrated into the existing layout)



Previous simulations: Compact LEBT + New RFQ
→ 20 mA behind RFQ !

HF-GL prototype for HSI upgrade



lens properties

r_{anode} : 85mm

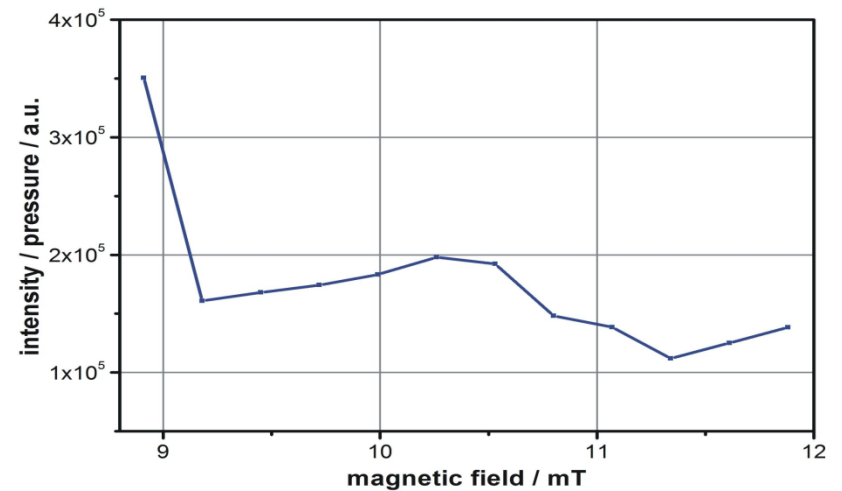
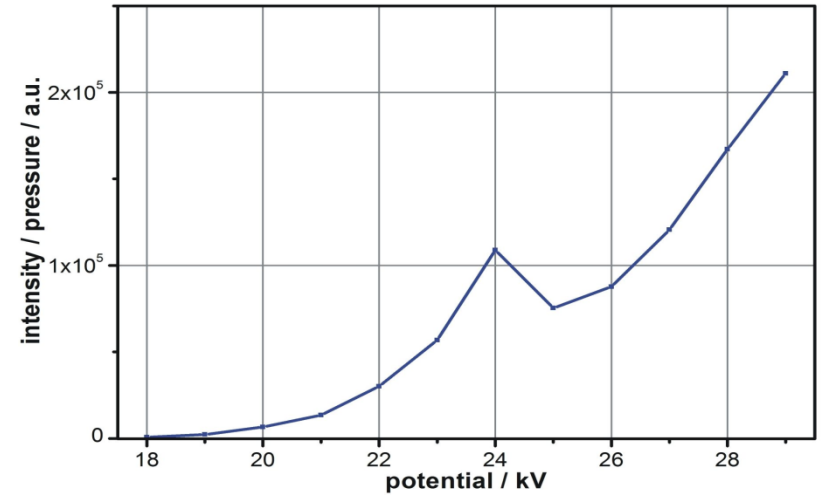
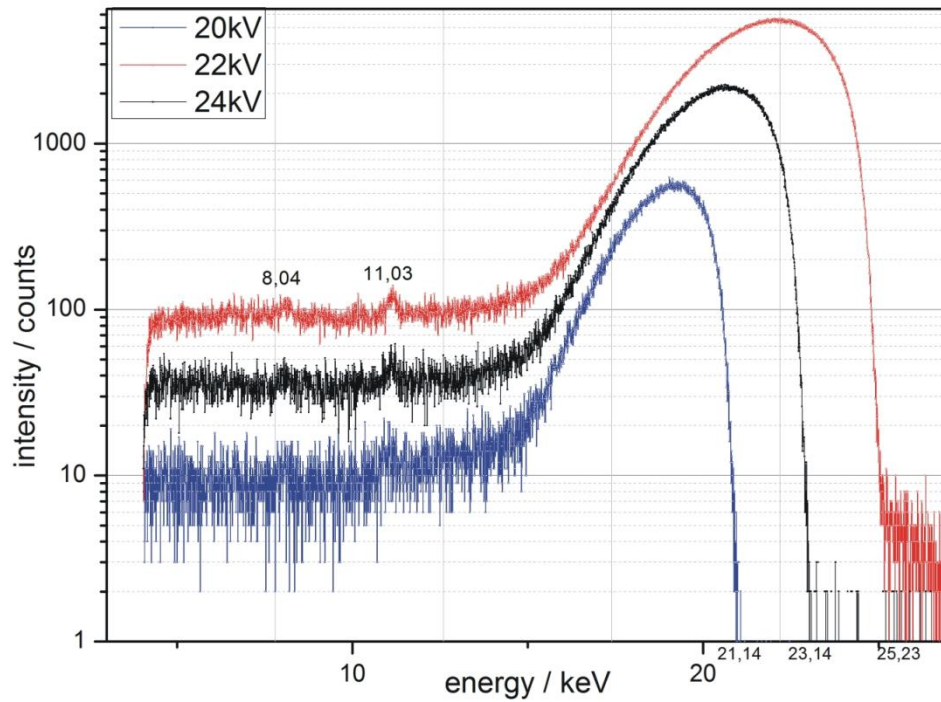
B_{max} : 50mT

Φ_{max} : 50kV

- ceramic insulator
- HV-contacting
- UH vacuum sealing

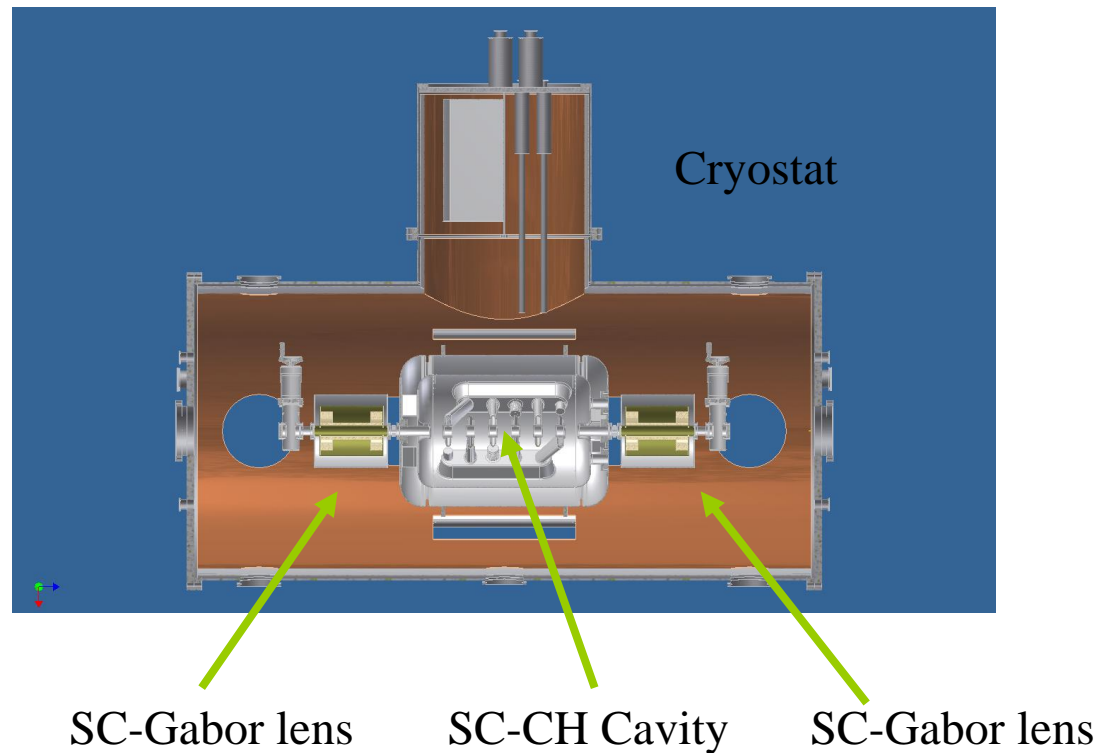
DN CF 160

emitted bremsstrahlung spectra



loss and production rates at pressures below 10^{-12} mbar

Is it possible to use a Gabor - lens in a cryogenic interior?



Thank you for your attention.

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